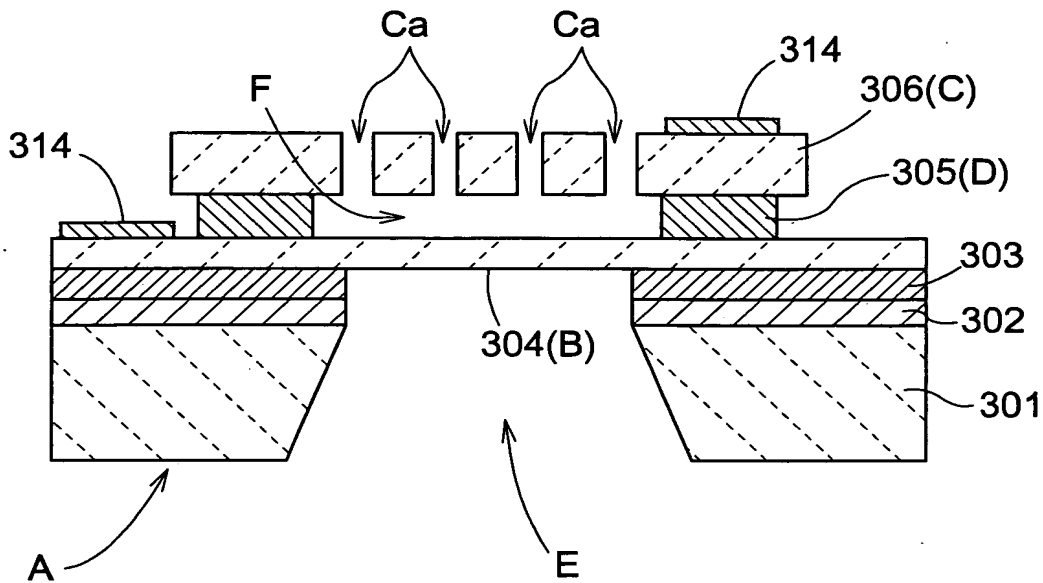


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FIG.1

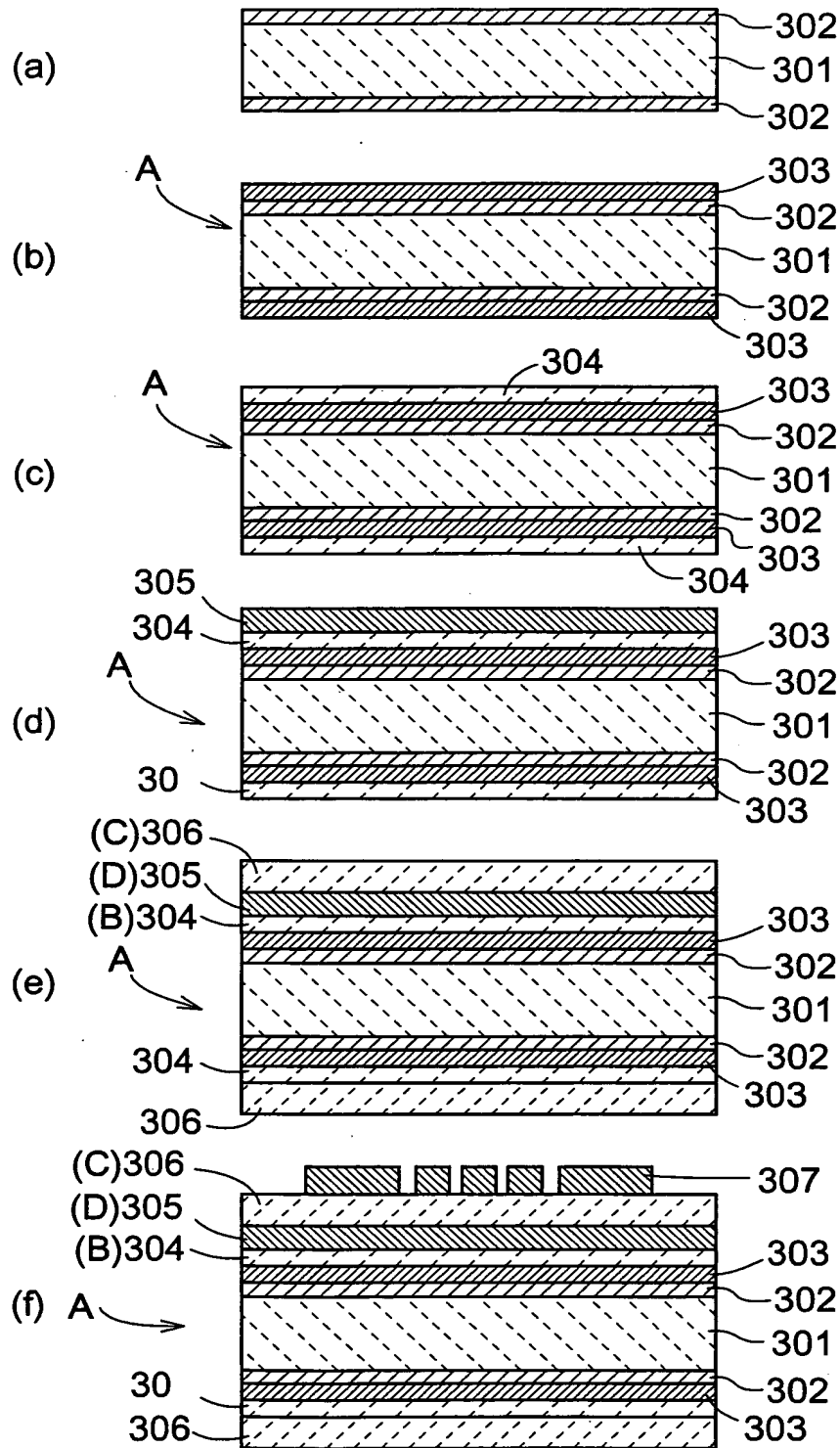


A: support substrate  
B: diaphragm  
C: back electrode  
D: spacer  
E: acoustic opening  
F: void area

301: monocrystal silicon substrate  
302: silicon oxide film  
303: silicon nitride film  
304: membrane, or polycrystal silicon film  
305: sacrificial layer  
306: polycrystal silicon film  
314: take-out electrode

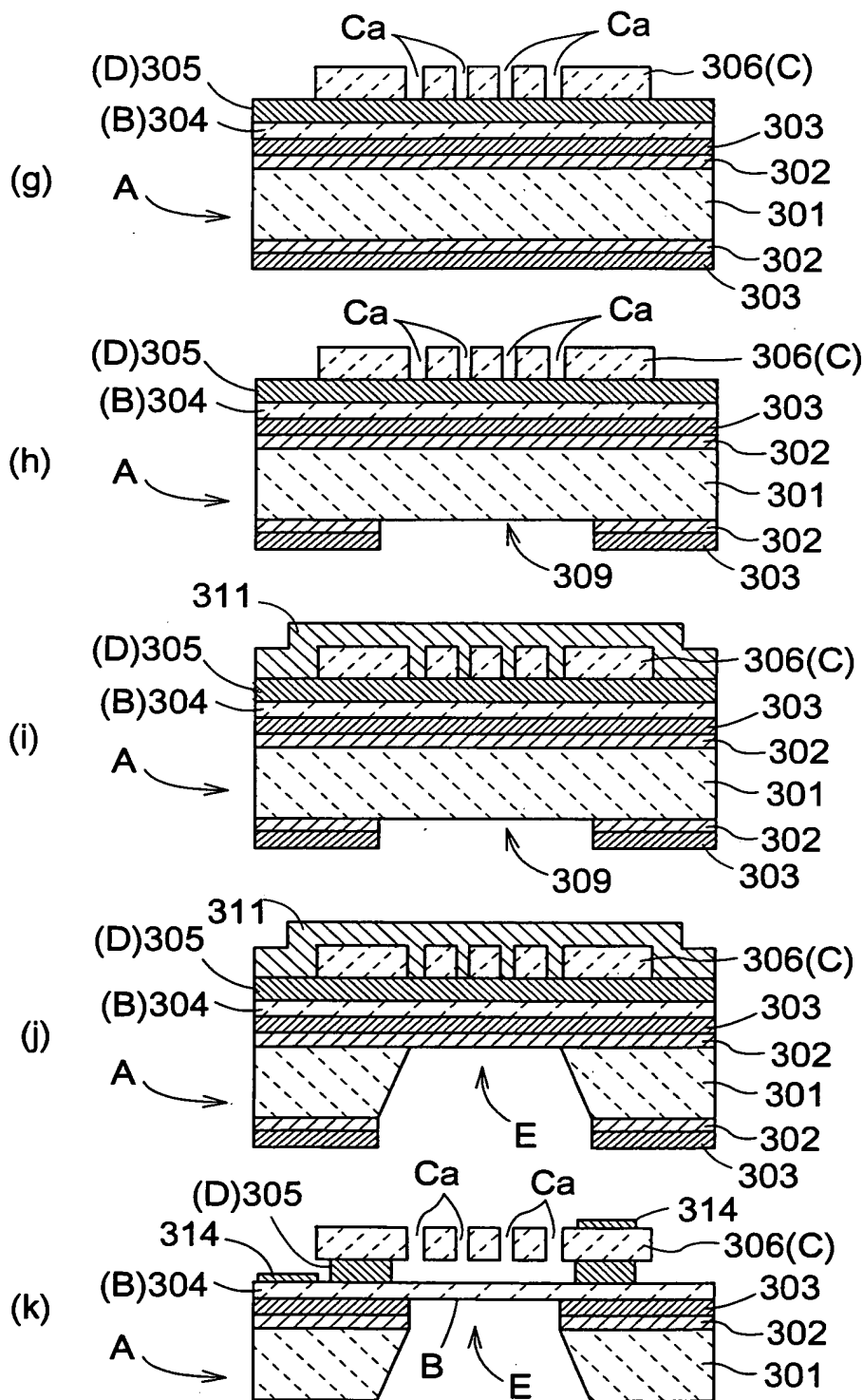
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FIG.2



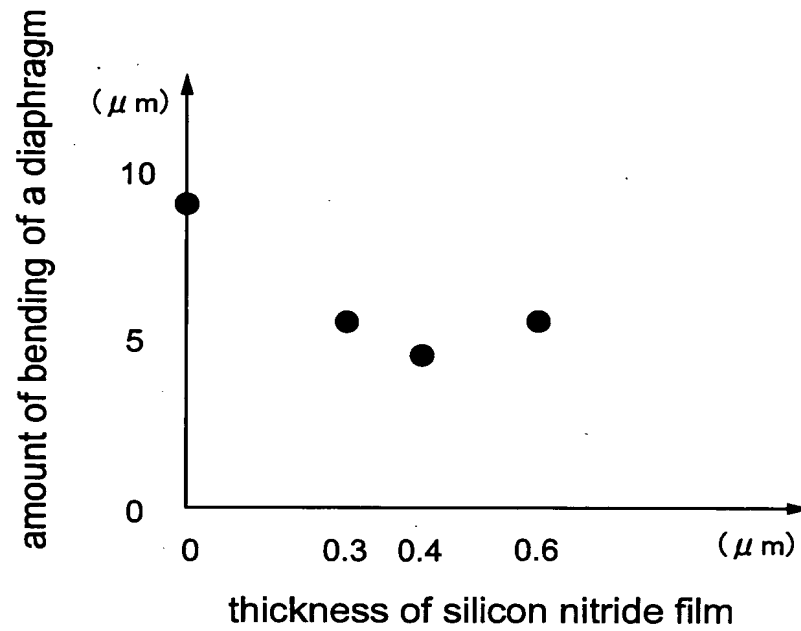
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FIG. 3



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FIG.4



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FIG.5

